



Serial No. 09/899,784

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re the Patent Application of

Inventor(s): Dong-Su Kim

Group Art Unit: 2823

Serial No.: 09/899,784

Examiner: Toledo, Fernando L

Filing Date: July 5, 2001

For: Method of Fabricating Silica Microstructures

CERTIFICATE OF MAILING UNDER 37 CFR 1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to the ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, D.C. 20231 on 10/15/02.

Steve Cha, Reg. No. 44,069
(Name of Registered Representative)

[Signature] 10/15/02
(Signature and Date)

Assistant Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

Sir:

In response to that Office Action dated July 17, 2002, please amend the above-identified application as follows (a marked-up version is attached as Appendix A):

IN THE TITLE

Please replace the title as follows:

-- "SILICA MICROSTRUCTURE AND FABRICATION METHOD THEREOF" --